Theometry Sensor for High Temperature and Harsh Fossil Environment Application



Novelty

- (1) Multi Sensors: 64 vs. 1 single sensor in ONE platform
- (2) MEMS Sensor: Leverage *unique* Ti based MEMS Technology:

Nano Structured-Titania Sensing Platform Increased the absorption surface by

x 2500/mm²



- (3) Sensitivity: Extremely sensitive with a shorter response time compared to any existing sensor technologies
- (4) Gas Selectivity : Capable to detect accurately a specific target gas in a mixed gases environment
- **(5) New Material**: Oxidation resistance alloy that withstands 1200 °C operating temperature and 1000 psi pressure.



- (6) Leverage Data Fusion: to post-process the collected data resulting a reliable output signals
- (7) Extremely Robust

PI : Payam Bozorgi, PhD PiMEMS, Inc payam@Pi-MEMS.com

MEMS Sensor Concept



Future Work (Phase II)

 Develop the Sensor Selectivity: Will incorporate into the sensing layer metallic (Al, Cr, Nb) or metal-oxide (Al₂O₃, Y₂O₃) dopants, or deposit a thin layer of noble metal (Pt, Pd)



(2) Develop the Data Fusion Algorithm :

Will develop multivariate Principal Component Analysis (PCA) and Partial Least Squares Algorithms to postprocessing 320 collected signals from each 64 individual sensor (5 sensors in one platform)

Subcontractor : Sebastien Dryepondt, PhD

Oak Ridge National Laboratory

(3) Design, Fabricate and Test the Prototype Sensor:

Will implement PiMEMS's patented fabrication processes to design and fabricated the Ti-based MEMS Gas Sensor and will test the fabricated prototype at NETL/PiMEMS facilities.

Phase I Achievements

(1) Developed a New Material Successfully integrated Nano-structured Titania (NST) thin film as the sensing platform to oxidation-resistant TiAlCrY and FeCrAlY coatings



SEM surface micrographs showing an NST layer deposited on a pre-oxidized FeCrAl coupons, annealed at 800°C, a) for 1h, b) for 15h



SEM surface micrographs showing an NST layer deposited on a TIAIC-coated Ti coupon pre-oxidized at 800°C for 1h. a) as fabricated NST layer, b) annealed at 800°C for 1h.

(2) Successfully developed an etching process to fabricate the micro pillars sensing platform on the developed alloy: 46-5Ti-37Al-17Cr-0.1Y



The developed process is scalable and enables to control the shape of the etched pillars



Micrographs of the pillars, 10um in diameter, 5 um in height formed by etching at the surface of a TICrAI coupons, a) well distributed arrays of pillars, b) back scattered SEM image showing the bi-phase structure of the TIAICr alloy and well defined pillars